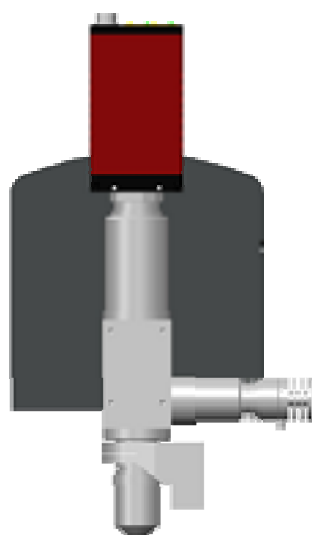
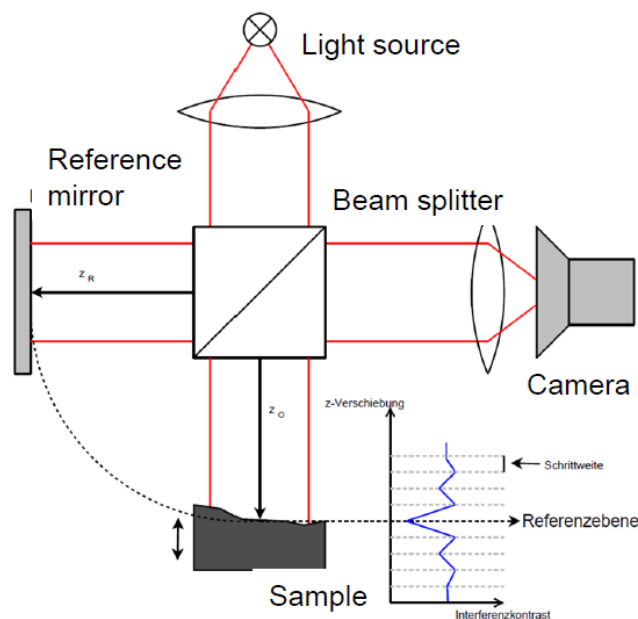


TRIMOS TR SCAN
Technology WLI
White Light Interferometry Technology



Technical specifications for WLI



White-light interferometry is among the proven optical measurement techniques for recording 3-D topographies with depth resolution in the lower nanometre range. The measurement points are acquired and processed in parallel, the height information can be gathered over a large area in a very short time.

Typical applications in research and in quality management are the characterisation of surfaces with different roughness values (wafer structures, mirrors, glass, metals), the determination of step heights and the precise measurement of curved surfaces, such as microlenses. The product family WLI offers innovative solutions utilising this measurement principle.

The control and analysis of the entire measurement process is done using the proven Trimos Nanoware software. The efficient, robust and highly accurate analysis algorithms are the result of extensive research and experience in this area.

OPTICAL PROBE	WLI 2.5x	WLI 5x	WLI 10x	WLI 20x	WLI 50x	WLI 100x
Resolution in Z	0.1 nm	0.1 nm	0.1 nm	0.1 nm	0.1 nm	0.1 nm
Resolution lateral (X/Y)	4.81 μm	2.77 μm	1.2 μm	0.9 μm	0.66 μm	0.52 μm
Vertical range	400 μm	400 μm	400 μm	400 μm	400 μm	400 μm
Measuring area range X/Y	~4536 μm x ~3447 μm	~2268 μm x ~1723 μm	~1134 μm x ~861 μm	~567 μm x ~430 μm	~226 μm x ~172 μm	~113 μm x ~86 μm
Optical zoom	2.5x	5x	10x	20x	50x	100x
Working distance	~10.3 mm	~9.3 mm	~7.4 mm	~4.7 mm	~3.4 mm	~2 mm